

ABSTRACT OF THE DISCLOSURE

A carrier robot system and a control method for a carrier robot enabling teaching even when an operator cannot approach
5 a teaching position for wafer conveyance are provided.

In a carrier robot system comprising a robot (1) which has a placement portion for placing an object presenting a low-profile form thereon and carries the object and a robot controller (9) for controlling the robot (1), a jig (3) mounted
10 on the placement portion of the robot and having an image pickup member (4), an image processing portion (8) for processing an image picked up by the image pickup member (4), and a superior control portion (10) for controlling the robot controller (9) and image processing portion (8) from a superior position are
15 provided.